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\*\*APPLICANTS Miyajima Yoshikazu; Ootuka Kazuhito; Emoto Keiji;

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\*\* FOREIGN APPLICATIONS VERIFIED:  
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PG-PUB DO NOT PUBLISH <input type="checkbox"/>	RESCIND <input type="checkbox"/>	ATTORNEY DOCKET NO 862.02476
Foreign priority claimed: <input type="checkbox"/> yes <input type="checkbox"/> no 35 USC 119 conditions met: <input type="checkbox"/> yes <input type="checkbox"/> no Verified and Acknowledged Examiners's initials		
TITLE: Exposure apparatus, device manufacturing method, semiconductor manufacturing factory, and exposure apparatus maintenance method		

IF ALLOWANCE MAILED DATE DUE DATE PAID		Assistant Examiner  Primary Examiner	CLAIMS ALLOWED Total Claims DRAWINGS Sheets Drawn Figures Drawn
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